

U.S. Department of Commerce, Patent and Trademark Office					Atty Docket No.		Serial No.	
					M-9131 US		Unknown	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT					Applicant			
(Use several sheets if necessary)					James M. Holden			
					Filing Date		Group	
					Herewith		Unknown	
U.S. Patent Documents								
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
ah	AA	4,999,010	Mar. 12, 1991	Mattson et al.	356	346	—	
ah	AB	6,075,612	Jun. 13, 2000	Mandella et al.	356	445	—	
oh	AC	6,084,662	Jul. 4, 2000	Seaburn	356	73	—	
	AD							
	AE							
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	AG							
	AH							
	AI							
	AJ							
	AK							
Foreign Patent Documents								
							Translation	
		Document	Date	Country	Class	Subclass	Yes	No
ah	AL	WO 00/12961	9 Mar 2000	WIP <del>PCT</del>	—	—	✓	
	AM							
	AN							
	AO							
	AP							
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)								
ah	AQ	Gamsky, C. et al., "Quantitative analysis of chemically amplified negative photoresist using mirror-backed infrared reflection absorption spectroscopy" SPIE Vol. 2438, Pages 143-152.						
oh	AR	Gamsky, C., "Reflectance FT-IR For Monitoring Chemical Reactions In Chemically Amplified Photoresists For 0.25 $\mu$ m X-Ray Lithography" UMI Dissertation Services, at the University of Wisconsin-Madison (1995), Pages 1-250.						
	AS							
Examiner		Christopher M. ...		Date Considered		8/28/03		
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.								

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2001  
P. Taylor

U.S. Department of Commerce, Patent and Trademark Office					Atty Docket No.		Serial No.	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)					M-9131 US		09/923,723	
					Applicant			
					James M. Holden			
					Filing Date		Group	
					August 6, 2001		Unknown	
U.S. Patent Documents								
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
ah	AA	5,889,593	Mar. 30, 1999	Bareket	356	445		
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	AJ							
	AK							
Foreign Patent Documents								
							Translation	
		Document	Date	Country	Class	Subclass	Yes	No
	AL							
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OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)								
ah	AQ	Harrison, D. et al., "Innovations in Lithography Metrology for Characterization of Phase-Shift Mask Materials" <i>SPIE</i> (2001) Pages 233-240.						
ah	AR	"n&k Analyzer 1512RT", downloaded 9/25/01 from < <a href="http://www.nandk.com/1512rt.html">http://www.nandk.com/1512rt.html</a> >, n&k Technology, Inc. (2001).						
	AS							
Examiner		Anodomenko		Date Considered		8/28/03		
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